

The schematic diagram illustrates a transfer robot system for a semiconductor device. On the left, a **TRANSFER ROBOT** is shown with a mechanical arm. The system includes a central horizontal processing chamber (16) with multiple internal components. A transfer arm (13) is positioned at the left entrance (5) of the chamber. A wafer (14) is shown being moved by the transfer arm. The chamber is connected to various gas supply systems: a main gas supply (3) at the bottom left, a secondary gas supply (17) at the bottom center, and a purge gas supply (9b) at the bottom right. These are connected to the chamber via valves and piping. A gas distribution head (8b) is located inside the chamber, with arrows indicating gas flow. A sensor or detector (18) is positioned above the wafer. A control unit (10b) is connected to the system. A dashed line (19) indicates a control or data path between the transfer robot and the system. Other components labeled include 1a, 2a, 4, 7b, 11b, and 20.